

IN THE U.S. PATENT AND TRADEMARK OFFICE
Express Mail Label No.: EL 640 011 113 US
Attorney Docket No.: OPS Case 529
April 3, 2001

Box Patent Application
Assistant Commissioner for Patents
Washington, DC 20231

Sir:

Transmitted herewith for filing is the ☒ utility ☐ design
patent application of:

Inventor(s): Toshiaki MOTONAGA; Norihito ITO; Chiaki
HATSUTA; Junji FUJIKAWA; Naoya HAYASHI;
Toshio ONODERA; Takahiro MATSUO; Toru
OGAWA; and Keisuke NAKAZAWA

For : HALFTONE PHASE SHIFTING PHOTOMASK AND BLANKS
FOR HALFTONE PHASE SHIFTING PHOTOMASK
THEREFOR AND A METHOD FOR FORMING PATTERN BY
USING THE HALFTONE PHASE SHIFTING PHOTOMASK

Pursuant to 37 CFR 1.53, the above-identified application is
being submitted without the filing fee, and it is respectfully
requested that this application be granted a serial number and
filing date and that the undersigned be notified of the date
by which the filing fee must be submitted. Enclosed are:

- ☒ Specification
- ☐ Declaration or Oath
- ☒ 11 Drawing Sheets ☒ Formal
☐ Informal
- ☒ Amendment Before First Office Action
- ☐ Information Disclosure Statement
- ☐ Assignment, with Recordation Form Cover Sheet. A check
for \$_____ is enclosed to cover the recording fee.
- ☒ Acknowledgment Postal Card
- ☒ Priority is claimed under 35 USC 119 based on Japanese
Application No. 2000-101907, filed April 4, 2000.
☒ A certified copy of the priority application is
enclosed.
- ☒ Pursuant to 37 CFR 1.53, this application is being filed
without the declaration or oath. Please notify the
undersigned of the due date for submitting the
declaration or oath. A Power of Attorney in favor of the
undersigned will be submitted later. Please direct all
telephone calls to the undersigned at telephone number
(616) 381-1156. Please address all correspondence to:

FLYNN, THIEL, BOUTELL & TANIS, P.C.
2026 Rambling Road
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The inventor(s) is(are) 1) Toshiaki MOTONAGA; 2) Norihito ITO; 3) Chiaki HATSUTA; 4) Junji FUJIKAWA; 5) Naoya HAYASHI; 6) Toshio ONODERA; 7) Takahiro MATSUO; 8) Toru OGAWA; and 9) Keisuke NAKAZAWA; residing at 1) Tokyo, Japan; 2) Tokyo, Japan; 3) Tokyo, Japan; 4) Tokyo, Japan; 5) Tokyo, Japan; 6) Kanagawa-ken, Japan; 7) Kanagawa-ken, Japan; 8) Kanagawa-ken, Japan; 9) Tokyo, Japan; having the following post office address(es): 1) c/o 1-1, Ichigaya-kagacho 1-chome, Shinjuku-ku, Tokyo 162-8001, Japan; 2) c/o 1-1, Ichigaya-kagacho 1-chome, Shinjuku-ku, Tokyo 162-8001, Japan; 3) c/o 1-1, Ichigaya-kagacho 1-chome, Shinjuku-ku, Tokyo 162-8001, Japan; 4) c/o 1-1, Ichigaya-kagacho 1-chome, Shinjuku-ku, Tokyo 162-8001, Japan; 5) c/o 1-1, Ichigaya-kagacho 1-chome, Shinjuku-ku, Tokyo 162-8001, Japan; 6) 103 Cosmo-Shonan, 3333 Kameino, Fujisawa-shi, Kanagawa-ken 252-0813, Japan; 7) 403 Sany-19, 1-22-4 Zengyo, Fujisawa-shi, Kanagawa-ken 251-0871, Japan; 8) 5-3-22 Shukugawara, Tama-ku, Kawasaki-shi, Kanagawa-ken 214-0021, Japan; and 9) 4-41-12 Nokata, Nakano-ku, Tokyo 165-0027, Japan; and all having the following citizenship: Japan.

[] Pursuant to 37 CFR 1.52, the enclosed application is in the form of a foreign language text:

[] An English translation and a statement that the English translation is accurate are enclosed.

[] Please notify the undersigned of the due date for submitting an English translation and a statement that the English translation is accurate.

Respectfully submitted,


Dale H. Thiel

DHT/jp

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Encl: Listed above

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09/03/01

PATENT APPLICATION

"Express Mail" Mailing Label No.: EL 640 011 113 US

Date of Mailing: April 3, 2001

Applicant(s): Toshiaki MOTONAGA et al.

Title: HALFTONE PHASE SHIFTING PHOTOMASK AND BLANKS FOR
HALFTONE PHASE SHIFTING PHOTOMASK THEREFOR AND A
METHOD FOR FORMING PATTERN BY USING THE HALFTONE PHASE
SHIFTING PHOTOMASK

Serial No.: Unknown

Filed: Unknown

Atty Docket No.: OPS Case 529

Assistant Commissioner for Patents

Washington DC 20231

EXPRESS MAILING CERTIFICATE

Sir:

I hereby certify that the attached paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR 1.10 on the date indicated above and is addressed to the Assistant Commissioner for Patents, Washington DC 20231.

FLYNN, THIEL, BOUTELL & TANIS, P.C.

By: Chia Skipper

Date: April 3, 2001

Document(s) attached: Patent Application Transmittal dated April 3, 2001, and enclosures

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